

Abstract of Disclosure

DEPOSITION CHAMBER AND METHOD OF USING THE SAME

The present invention provides a deposition chamber and a method of using the same. The deposition chamber includes a heater base and at least a sensor. The heater base includes a heater plate and a heater lifter, wherein the heater lifter supports the heater plate, and the heater plate and a part of the heater lifter are enclosed in a chamber body. The sensor is disposed on the heater lifter to monitor the leveling of the heater.

Figure 1